Optical Hyperdoping: Transforming Semiconductor Band Structure for Solar Energy Harvesting

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irradiate with 100-fs 10 kJ/m² pulses

TRUST





absorptance
$$(1 - R_{int} - T_{int})$$



absorptance
$$(1 - R_{int} - T_{int})$$



R.



absorptance
$$(1 - R_{int} - T_{int})$$



band structure changes: defects and/or impurities



optical hyperdoping puts 2% of sulfur in 200-nm surface layer





open questions

- how do the impurities get incorporated?
- can we use optical hyperdoping for solar cells?

Outline

3

DA

CHEY'S

126

• goals

optimizing dopant profile

1/24/03 9 kJ/m (+ Sam

intermediate band

1.20

interesting properties due to intermediate band



generalize

Outline

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De

(OIST'S

950 P

• goals

optimizing dopant profile

c/ 200

1/24/03 9 kJ/m cr sam

intermediate band (

Theoretical agenda

- explain enhanced doping
- optimize dopant profile for device design
- design process for optimal dopant profile

why does enhanced doping occur?

physical mechanisms:

- melting and resolidification of thin layer
- sulfur diffusion into liquid silicon
- incorporation into solid during resolidification

why does enhanced doping occur?

mathematical model:

- calculate dynamics of two fields
- temperature T(x,t)
- sulfur concentration c(x,t)

calculation step 1: temperature profile set up by laser

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calculation step 2: solid melts, solute incorporated

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melting:

• heat diffusion $T_t = D_{th} T_{xx}$ • energy balance $L_V \dot{h} = [[-\kappa_T T_x]]$

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incorporation: • solute diffusion $c_t = Dc_{xx}$ • mass balance $[[c]]\dot{h} = [[-D c_x]]$

calculation step 2: solid melts, solute incorporated

melting:

• heat diffusion $T_t = D_{th} T_{xx}$ • energy balance $L_V \dot{h} = [[-\kappa_T T_x]]$

incorporation: • solute diffusion $c_t = Dc_{xx}$ • mass balance $[[c]]\dot{h} = [[-D \ c_x]]$ $T = T_{melt} + mc^L(h) - \mu \dot{h}$

boundary condition critically affects dopant profile

two scenarios
two scenarios

constant concentration























cross-sectional Transmission Electron Microscopy

M. Wall, F. Génin (LLNL)

μm









secondary ion mass spectrometry







appears to be closer to constant flux

Outline

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950 P

• goals

optimizing dopant profile

C/ 243

1/24/03 9 kJ/m (+ same

intermediate band

what dopant states/bands cause IR absorption?

1 part in 10⁶ sulfur introduces donor states in gap



Janzén et al., Phys. Rev. B 29, 1907 (1984)

absorptance
$$(1 - R_{int} - T_{int})$$



10⁻⁶ sulfur doping



laser-doped S:Si



laser-doped S:Si



laser-doped S:Si



isolate surface layer for Hall measurements

device layer

buried oxide

silicon substrate

isolate surface layer for Hall measurements



device layer buried oxide

silicon substrate

isolate surface layer for Hall measurements

laser doped region

buried oxide

silicon substrate

isolate surface layer for Hall measurements



isolate surface layer for Hall measurements





Hall measurements



transition to metallic behavior at high doping



can we understand this intermediate band

using atomistic modeling?

density of states




Intermediate band

recombination rate





change dopant/substrate combination

What's next?

optimal dopant profile is flat





change incorporation process:

•electrospray

• pulse sequence design

Acknowledgments

